



PDMS activation

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Summary:
This document describes oxygen plasma used to activate PDMS

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1 Associated Documents & References

MSDS if chemicals or gas involved.
Phantom etcher standard operating procedure
Rules and procedures of cleanroom

2 Equipment Used

Phantom Etcher (www.triontech.com) in Bahen Cleanroom. This equipment has to be reserved through the online resource scheduler. If you need to be assisted by the technician, check availability with him before reserving the equipment. Users have to go through regular training before using this equipment alone.



3 Verifications Prior to Processing

Chamber clean. No air leaks into etcher.

4 Recipe description

(We thank Dr. Tong JianHua (Prof. Sun's group, MIE) for the basic recipe)

Set up Phantom etcher with the following parameters
pressure 47 mTorr, RIE 270 watts, oxygen 13 sccm CHF₃ 39 sccm

Run samples for 300 seconds.

Depending on the sample size and thickness, sample may get hot and melt so trial runs to determine optimum time are required.

5 Technical Data

6 Measurements & Statistical Process Control

7 Record of Revisions

Rev. 0

First Edition